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Attorney Docket No. D/98706R

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Philip D. Floyd, *et al.*

Application No.: Not yet assigned

Group:

Filed: Concurrently herewith

Examiner:

Title: METHOD AND APPARATUS FOR AN INTEGRATED LASER BEAM SCANNER

Commissioner for Patents  
Washington, D.C. 20231

Sir:

**PRELIMINARY AMENDMENT UNDER 37 C.F.R. § 1.173(b)**  
**ACCOMPANYING REQUEST FOR REISSUE OF U.S. PATENT NO. 6,002,507**

Please enter this Preliminary Amendment into the file of the accompanying U.S. Patent Reissue Application.

**IN THE CLAIMS:**

Please add new claims 21-36 as follows:

21. (NEW) A MEMS formation method including:
- providing a SOI wafer including a single crystal silicon layer attached to an insulator layer;
  - forming at least one first MEMS component by patterning the single crystal silicon layer;
  - and
  - depositing at least one layer of polysilicon on the patterned single crystal silicon.
22. (NEW) The method of claim 21 further comprising forming at least one second MEMS component by patterning the polysilicon.